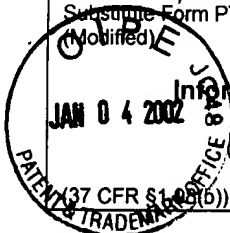


Substitute Form PTO-1449
(Modified)U.S. Department of Commerce
Patent and Trademark OfficeAttorney's Docket No.
12816-021001Application No.
09/898,909**Information Disclosure Statement
by Applicant**

(Use several sheets if necessary)

Applicant
Detlef WeberFiling Date
July 3, 2001Group Art Unit
2811**U.S. Patent Documents**

Examiner Initial	Desig. ID	Patent Number	Issue Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

Foreign Patent Documents or Published Foreign Patent Applications

Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
pc	AL	EP 0 989 609 A1	03/29/2000	EPO	H01L	23/522		
	AM							
	AN							
	AO							
	AP							

Other Documents (include Author, Title, Date, and Place of Publication)

Examiner Initial	Desig. ID	Document
pc	AQ	Rossnagel, S.M., "Filling dual damascene interconnect structures with AlCu and Cu using ionized magnetron deposition", <i>J. Vac. Sci. Technol.</i> B 13:125-129, (1995)
	AR	
	AS	
	AT	

Examiner Signature

DHAT Y. CAO

Date Considered

12/30/02

EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.